

Nanoscopy

Marcel, Wolfgang

Biomolecular Photonics, Bielefeld University

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- 1 SIM reconstruction algorithm
 - Image formation in SIM
 - Fourier space decomposition
 - Measurement with structured illumination
 - Illumination in Fourier space
 - Illumination parameter estimation
 - Fourier space shifts and separation

- 2 Summary and Outlook

Sorry, some math...

$$\begin{aligned}\frac{\partial}{\partial \theta} \mathbb{M}T(\xi) &= \frac{\partial}{\partial \theta} \int_{\mathbb{R}^n} T(x) f(x, \theta) dx = \int_{\mathbb{R}^n} \frac{\partial}{\partial \theta} T(x) f(x, \theta) dx \\ \frac{\partial}{\partial a} \ln f_{a, \sigma^2}(\xi_1) &= \frac{(\xi_1 - a)}{\sigma^2} f_{a, \sigma^2}(\xi_1) = \frac{1}{\sqrt{2\pi\sigma}} \exp\left\{-\frac{(\xi_1 - a)^2}{2\sigma^2}\right\} \\ \int_{\mathbb{R}^n} T(x) \cdot \frac{\partial}{\partial \theta} f(x, \theta) dx &= \mathbb{M}\left(T(\xi) \cdot \frac{\partial}{\partial \theta} \ln L(\xi, \theta)\right) \\ \int_{\mathbb{R}^n} T(x) \cdot \left(\frac{\partial}{\partial \theta} \ln L(x, \theta)\right) \cdot f(x, \theta) dx &= \int_{\mathbb{R}^n} T(x) \cdot \left(\frac{\partial}{\partial \theta} \ln L(x, \theta)\right) \cdot f(x, \theta) dx \\ \frac{\partial}{\partial \theta} \mathbb{M}T(\xi) &= \frac{\partial}{\partial \theta} \int_{\mathbb{R}^n} T(x) f(x, \theta) dx = \int_{\mathbb{R}^n} \frac{\partial}{\partial \theta} T(x) f(x, \theta) dx \\ &= \int_{\mathbb{R}^n} T(x) \cdot \left(\frac{\partial}{\partial \theta} \ln L(x, \theta)\right) \cdot f(x, \theta) dx = \int_{\mathbb{R}^n} T(x) \cdot \left(\frac{\partial}{\partial \theta} \ln L(x, \theta)\right) \cdot f(x, \theta) dx\end{aligned}$$

Math (from [here](#))

$$M_I(x, y) = \int_{S_z} \text{PSF}(x, y, z) * (I_I(x, y, z) \cdot S(x, y, z)) dz \quad (1)$$

$$I(x, y, z) = \text{PSF}_{\text{ex.}}(x, y, z) * I'(x, y, z) \quad (2)$$

- Interested in: **Sample response** (fluorescence density) $S(x, y, z)$.
- Limited by: PSF, i.e. Abbe limit lateral, background axial
- All SIM approaches:
 - ▶ Obtain $S(x, y, z)$
 - ▶ by combining multiple measurements M_I
 - ▶ for different illuminations $I_I(x, y, z)$
- **Keep in mind:** Illumination also limited by $\text{PSF}_{\text{ex.}}$.

Solve for $S(x, y, z)$

$$M_I(x, y) = \int_{S_z} \text{PSF}(x, y, z) * (I_I(x, y, z) \cdot S(x, y, z)) dz \quad (3)$$

$$I(x, y, z) = \text{PSF}_{\text{ex.}}(x, y, z) * I'(x, y, z) \quad (4)$$

- Convolution integral: No direct solution for $S(x, y, z)$
- Iterative solvers possible, but that is more advanced
- Direct solution
 - ▶ possible for specific forms of $I_I(x, y, z)$
 - ▶ by decomposition in Fourier space

Decomposition in Fourier space

$$\tilde{M}_l(k_{x,y}) = \int_{S_z} \text{OTF}(k_{x,y,z}) \cdot \left(\tilde{I}_l(k_{x,y,z}) * \tilde{S}(k_{x,y,z}) \right) dz \quad (5)$$

$$\tilde{I}(k_{x,y,z}) = \text{OTF}_{\text{ex.}}(k_{x,y,z}) \cdot \tilde{I}'(k_{x,y,z}) \quad (6)$$

- In Fourier space: $I(k_{x,y,z})$ folds with $S(k_{x,y,z})$
- Assume $I(k_{x,y,z}) = \sum_i \delta_i(k_{x,y,z})$
- Then M_l given by
 - ▶ Finite sum of shifted copies of $S(k_{x,y,z})$
 - ▶ Each shift position given by $k_{x,y,z}$ in $\delta_i(k_{x,y,z})$
- Collect as many M_l as there are $\delta_i(k_{x,y,z})$
→ directly solvable for $S(k_{x,y,z})$
- 2D SIM: 2 peaks from sin, 1 peak from DC

Step 1: Measurement for structured illumination

Regular illumination pattern

Use

$$I_l(x, y) = \frac{I_0}{2} \cdot [1 + \sin((2\pi \cdot p + \phi)/\kappa)]$$

where

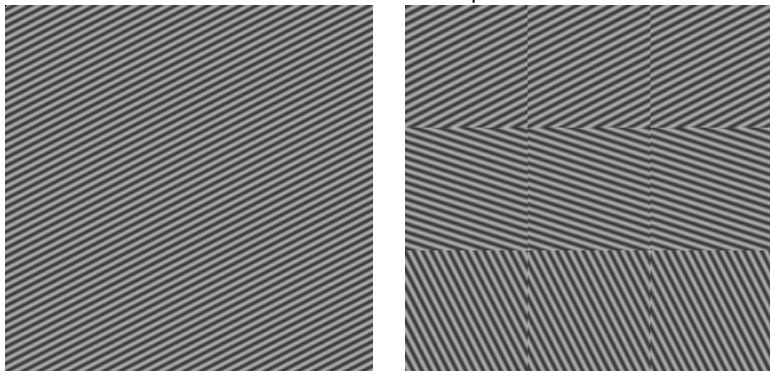
$$p = x \cdot \cos(\alpha) + y \cdot \sin(\alpha)$$

Multiple measurements

- Use multiple angles α for illumination
Typically 3 or 4, evenly spaced
- For each angle, illuminate with (at least) 3 phases $\phi = \frac{0}{3}\pi, \frac{2}{3}\pi, \frac{4}{3}\pi$
 - ▶ Phases not evenly spaced: loss of SNR
 - ▶ More than three phases: Reconstruction gets over-defined, but still possible
- Number of angles: Full resolution enhancement along each angle α .

Step 1: Illumination pattern

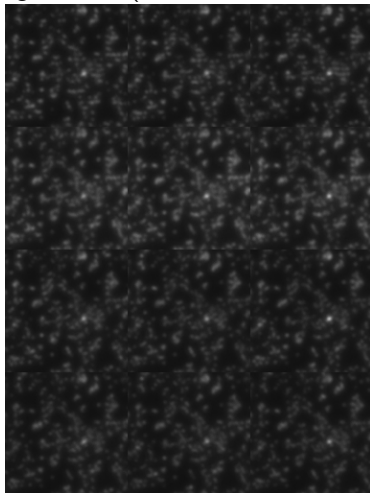
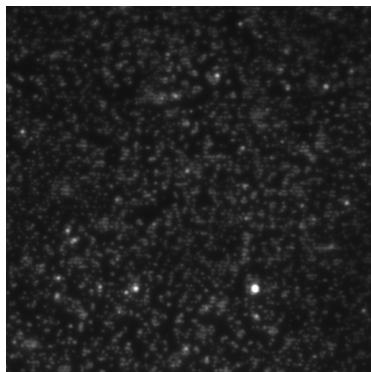
Simulated illumination pattern



Left: First illumination pattern. Right: Montage of all illumination patterns

Step 1: Measurement (2D SIM)

Test surface dye-filled beads. Pattern spacing: 256 nm ($\sim 86\%$ of resolution limit).

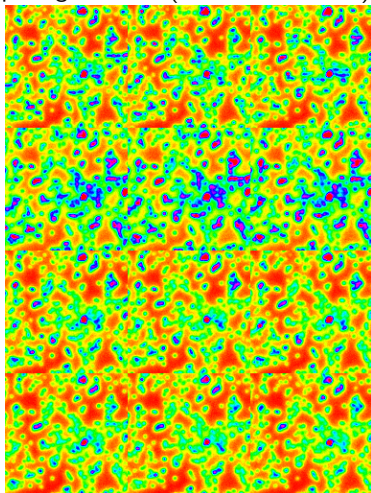
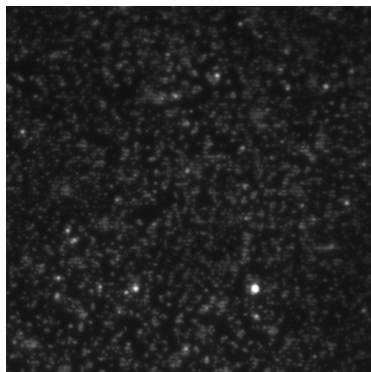


Left: First illumination pattern. Right: Cut-out, montage of all patterns

Any visible variation between the different patterns?

Step 1: Measurement (2D TIRF SIM)

Test surface dye-filled beads. Pattern spacing: 256 nm (at resolution limit).



Left: First illumination pattern. Right: Cut-out, montage with spectrum LUT

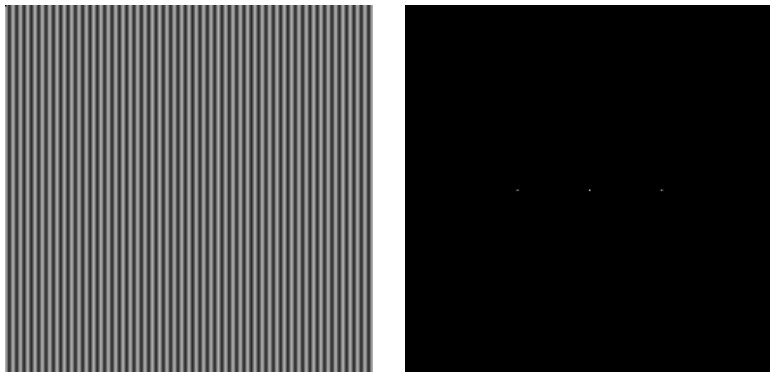
Look closely at the bright structures. . .

Step 2: Illumination in Fourier space

$$I_l(x, y) = \frac{I_0}{2} \cdot [1 + \sin((2\pi \cdot \rho + \phi)/\kappa)]$$

where

$$\rho = x \cdot \cos(\alpha) + y \cdot \sin(\alpha)$$



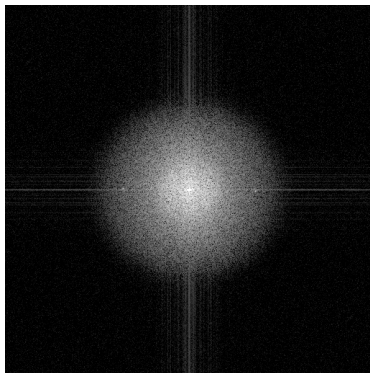
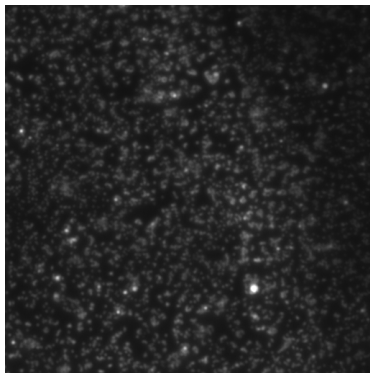
Left: Illumination pattern. Right: FFT / FHT power spectrum

Three dots in FFT

Step 2: Illumination in Fourier space

$$\tilde{M}_I(k_x, k_y) = \text{OTF} \cdot \left(\tilde{S}(k_x, k_y) * \tilde{I}_I(k_x, k_y) \right)$$

Test surface



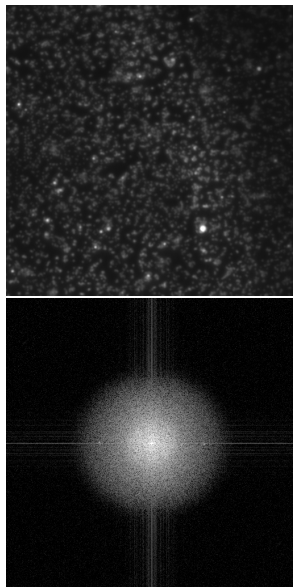
Left: Illumination pattern. Right: FFT / FHT power spectrum

Fourier space reveals the illumination pattern¹.

¹but only because $\kappa \sim 0.8\kappa_{\max}$

Step 2: Acquire parameters

- Three peaks in FFT power spectrum:
Center "DC" and symmetric $\sin(2\pi \cdot p + \phi)$ -contribution.
- Position directly translates to κ , α .
- The phase ϕ is contained in $z = r \cdot e^{i\phi}$,
as the FFT yields a complex number.
However, it is easily distorted by other
structures in the sample.



Step 3: Decompose the measurements

Measurement

Three phases ϕ_0, ϕ_1, ϕ_2 for illumination, each row in K represents one measurement:

$$K = \begin{pmatrix} 1 & \frac{1}{2}e^{i\phi_0} & \frac{1}{2}e^{-i\phi_0} \\ 1 & \frac{1}{2}e^{i\phi_1} & \frac{1}{2}e^{-i\phi_1} \\ 1 & \frac{1}{2}e^{i\phi_2} & \frac{1}{2}e^{-i\phi_2} \end{pmatrix}$$

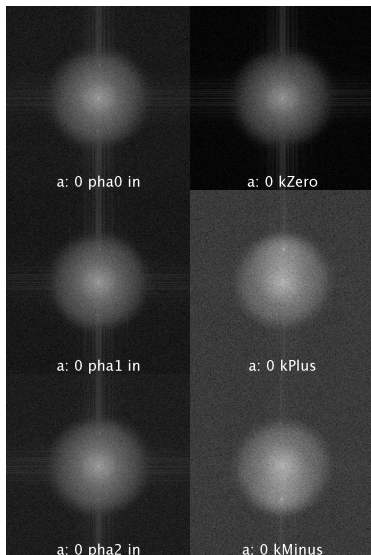
Columns: DC contributions, two symmetric contributions from the sinusoidal form.

Decomposition

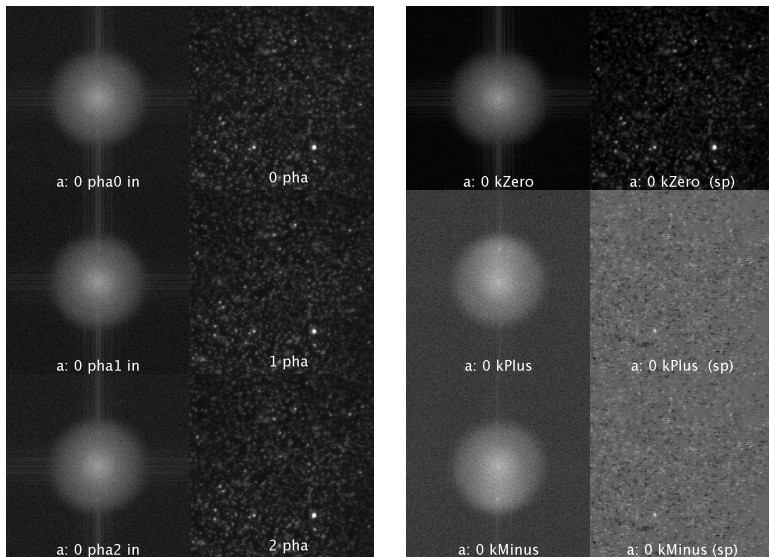
Invert^a K to K^{-1} .

Via K^{-1} , get the DC contribution (wide-field) and higher frequencies.

^a 3×3 matrix, otherwise Moore-Penrose pseudo inverse



Step 3: Spatial results of decomposition



DC component reconstructs to an images with wide-field characteristics.
Sinusoidal components not yet meaningful, but: κ and α have not been used so far.



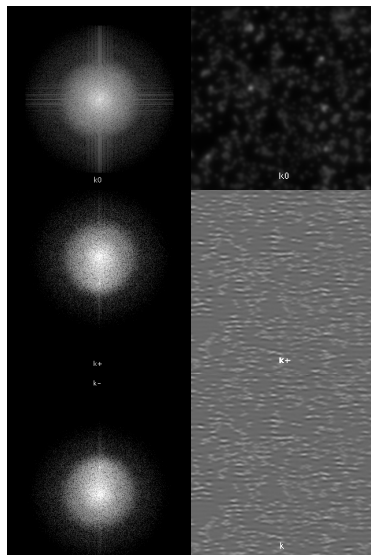
Step 3: Shifting frequency components

Compute shift

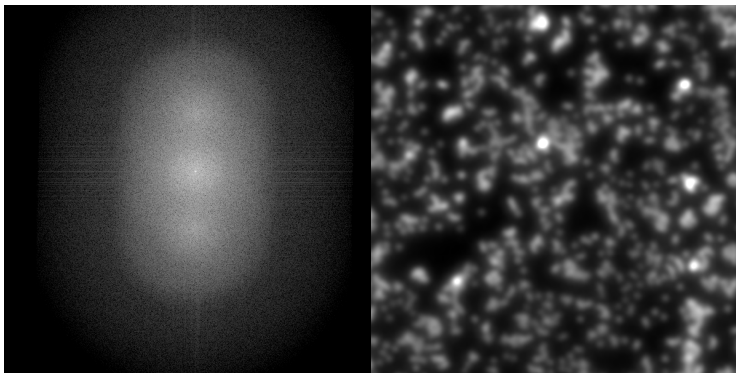
- DC component: Widefield, done.
- Two symmetric components:
 $\sin((2\pi \cdot \rho + \phi)/\kappa)$, where
 $\rho = x \cdot \cos(\alpha) + y \cdot \sin(\alpha)$
- Shift these contributions by $\pm\kappa, \alpha$

Result

- Pixels needed for shift: Resolution enhancement
- $+\kappa$ and $-\kappa$: contain the same information by definition
- Spatial transformation: Structure becomes apparent



Step 3: Added frequency components



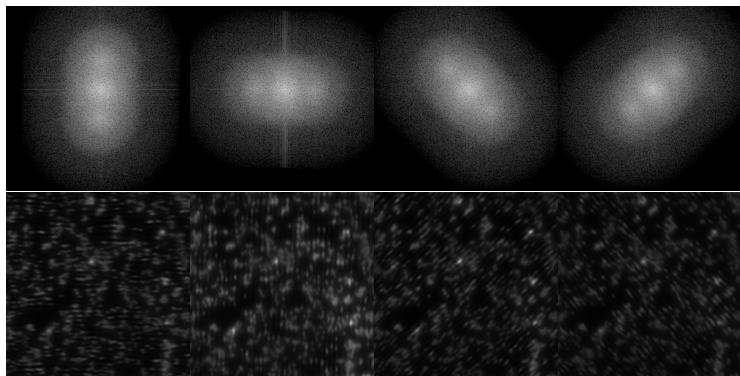
Add up the DC and shifted sinusoidal components. Result: Resolution-enhancement along illumination pattern direction α .

Interim result

- Sinusoidal pattern², 3 contributions in Fourier space
- Matrix inversion, decomposition and shift
- Resolution enhancement along the pattern direction
- **Number of phases:** At least 3, more lead to an over-defined matrix
- When measuring these 3 phases, κ and α have to be fixed, phases should be evenly spaced.
- **Number of angles:** Arbitrary, but usually 3 or 4 to fill the Fourier space.
- κ may change between angles α .
- **Resolution enhancement:** Directly given by pattern spacing κ .

²Other pattern: How does their Fourier transform look like?

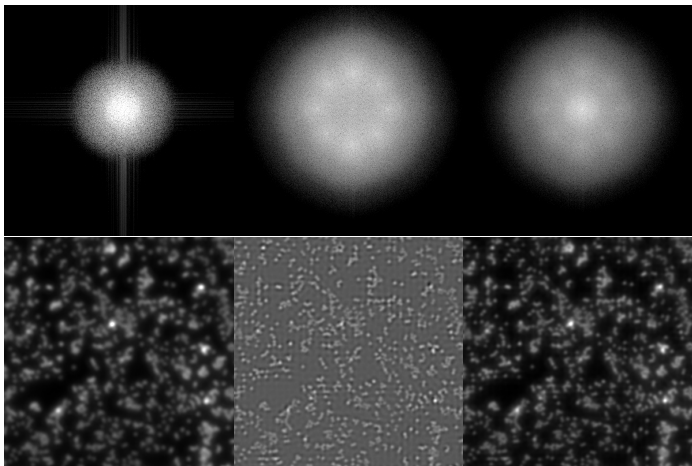
Step 4: Measure for multiple angles α



Three angles α . Resolution enhancement along each angle of the pattern. Next step: Combine these spectra.

Step 4: Combine all angles

$$\tilde{M}_I(k_x, k_y) = \text{OTF}(k_x, k_y) \cdot \left(\tilde{S}_I(k_x, k_y) * \tilde{I}(k_x, k_y) \right)$$



Low, high and all frequency components

Low frequency widefield, high frequency additional information, all frequencies combined.
Close, but not quite right. What is missing?

Step 5: OTF frequency filtering

$$\tilde{M}_l(k_x, k_y) = \text{OTF} \cdot \left(\tilde{S}(k_x, k_y) * \tilde{I}_l(k_x, k_y) \right)$$

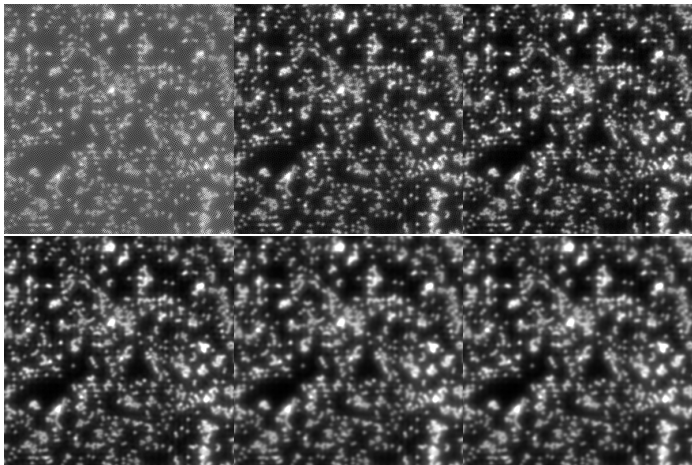
- So far, result looks better, but not quite right
- Transfer function: Not only limits resolution, but dampens high frequencies
- This leads to problems when shifting components around
- Solution: Divide by OTF in frequency domain.
- However: Low to zero regions in OTF will cause artifacts
- Full solution: frequency filtering

Step 5: (modified/generalized) Wiener filter

$$\tilde{R}(k_x, k_y) = \sum_l \frac{OTF(k_x, k_y) \tilde{M}_l(k_x, k_y)}{OTF^2(k_x, k_y) + \omega}$$

- Multiply by OTF and divide by OTF^2 , thus: Result without frequency dampening
- Numerator: One contribution of OTF is multiplied in post-processing, one is inherent to the measurement.
- Parameter ω : Artificial high-frequency dampening.
Dominates in regions of a low OTF, with quadratic response.
- Determining the OTF: Big difference between 2D and 3D:
2D: Use any OTF (Gaussian, Bessel, ...) with a somewhat matching FWHM
3D: Measure a quite exact OTF along the axial direction.
- There are more involved filtering methods available (e.g. iterative ones like total variations)
But: *No further information is generated by filtering.*

Step 5: Result of Wiener filtering



Reconstruction with different Wiener filter settings:

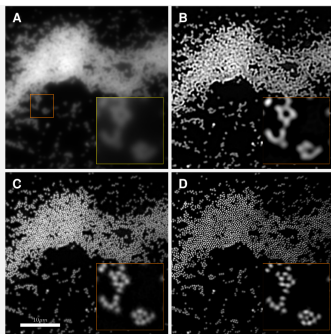
0.05, 0.1, 0.5, 2, 10, 50

Step 5: Apotization

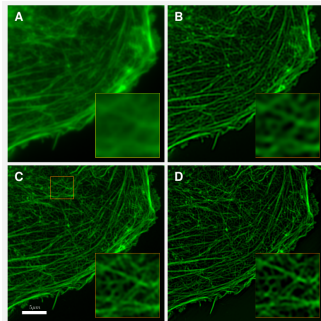
$$\tilde{S}'(k_x, k_y) = \text{APO} \cdot \sum_l \frac{\text{OTF}(k_x, k_y) \tilde{M}_l(k_x, k_y)}{\text{OTF}^2(k_x, k_y) + \omega}$$

- After the filtering step, $R(k_x, k_y)$ now has no "natural" dampening of higher frequencies.
- This leads to harsh contrasts that would not be obtained by a higher resolution microscope
- Fix: Multiply an apotization function APO to the result
- APO: An artificial OTF, dampening high frequency components the same way a microscope would
- FWHM of the APO: motivated by the higher resolution limit set through the original OTF, κ and (to a lesser degree) ω .
- In practice: Start with $\text{FWHM}_{\text{APO}} = 2 \cdot \text{FWHM}_{\text{OTF}}$, tweak ω and APO with lots of leeway.

Step 5: Final result



200 nm Tetraspeck beads, excitation at 643 nm, measured on a DeltaVision OMX (GE LifeScience). Wide-field [A], filtered wide-field [B], single slice 2D SIM-reconstruction by our software [C], 3D SIM reconstruction of the same slice, by SoftWORX (Applied Precision/GE LifeScience) [D].



Wide-field [A], filtered wide-field [B], single slice 2D SIM reconstruction by our software [C], 3D SIM reconstruction of the same slice, by SoftWORX (Applied Precision/GE LifeScience) [D]. LSEC actin filaments are labeled with AlexaFluor 488 / Phalloidin, measured on a DeltaVision OMX (GE LifeScience).

Summary and Outlook

Algorithm presented today

- Sinusoidal form needed
- 2D since ≈ 2000 ,
3D since ≈ 2008 .
- In Bielefeld: OMX and self-made setup
- In development: Free, open-source reconstruction software

Outlook next lectures

- SIM: Extension to 3D
- SIM: Iterative solvers
- Localization microscopy